U.S. Department of Commerce, Patent and Trademark Office		Application No.:	Unknown
		Filing Date:	Unknown
		First Named Inventor:	Jaime Poris
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Group Art Unit:	Unknown
(Use several sheets if necessary)		Examiner Name:	Unknown
		Confirmation No.:	Unknown
Copies of References located in Parent Application Serial No. 09/724,813		Attorney Docket No.:	NAN042-1D US

U.S. Patent Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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	2.	5,348,002	9/20/1994	Caro	128	633	
	3.	5,555,471	10-Sep-96	Xu et al.	356	357	
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							Translation
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	14.	EL 0 831 295 A1	3/25/1998	EP				
	15.	EP 0 982 774 A2	3/1/2000	EP				
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Examiner	Date Considered

*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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